

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	5102	roller same position same (semiconductor wafer substrate)	US-PG&UB USPAT	OR	ON	2007/03/04 16:33
S2	1765	roller same position same (semiconductor wafer substrate)	US-PG&UB	OR	ON	2008/03/04 16:34
S3	1740	roller with position with (semiconductor wafer substrate)	US-PG&UB USPAT	OR	ON	2008/03/04 16:34
S4	605	roller with position with (semiconductor wafer substrate)	US-PG&UB	OR	ON	2008/03/04 16:35
S1	1	"5661642".pn.	USPAT	OR	ON	2007/08/07 13:03
S2	41	"10330843" "10261839" "10330897" "10404692" "10404270" "10603427" "10606022" "10607611" "10611140" "10742303".plan.	US-PG&UB USPAT	OR	ON	2007/03/29 10:59
S3	0	"10330843" "10261839" "10330897" "10404692" "10404270" "10603427" "10606022" "10607611" "10611140" "10742303".plan.	US-PG&UB USPAT	OR	ON	2007/03/29 11:00
S4	0	"10330843" "10261839" "10330897" "10404692" "10404270" "10603427" "10606022" "10607611" "10611140" "10742303".PN.	US-PG&UB	OR	OFF	2007/03/29 11:01
S5	0	("10330843") or ("10261839" "10330897" "10404692" "10404270" "10603427" "10606022" "10607611" "10611140") or ("10742303").PN.	US-PG&UB	OR	OFF	2007/03/29 11:01
S6	0	("10330843") or ("10261839" "10330897" "10404692" "10404270" "10603427" "10606022" "10607611" "10611140") or ("10742303").PN.	US-PG&UB	OR	OFF	2007/03/29 11:29
S7	1	"6493040".PN.	USPAT	OR	OFF	2007/03/29 11:29
S8	16	"6446358" "6629540" "4066670" "5294257" "6514570" "6541998" "6391166" "5660642" "5607522" "6398975" "6491764" "4838289" "521774" "5705223" "5945351" "5997653".pn.	USPAT	OR	ON	2007/08/09 10:56
S9	15	"20020121290" "20020125212" "20030091754" "20030092264" "20040060573" "20040069519" "20040069329" "20040136494" "200400178060" "20040182422" "20050132515" "20050139316"	US-PG&UB USPAT	OR	ON	2007/08/07 13:17
S10	386	"1347952.col.	US-PG&UB USPAT	OR	ON	2007/08/07 13:46
S11	2	"6491764" "6398975".pn.	US-PG&UB USPAT	OR	ON	2007/08/07 13:46
S12	32	"5190086" "5351360" "5378291" "5415691" "5529626" "5591262" "5668322" "5695617" "5772764" "5803970" "5826129" "5853961" "5871564" "5923915" "5937223" "5997653".PN. OR ("6247479").UPRN.	US-PG&UB USPAT; USOCR	OR	ON	2007/08/08 08:05
S13	1	substrate wafer semiconductor) and (docking adj station) and (proximity adj head) and (coupon adj magazine)	US-PG&UB USOCR	OR	ON	2007/08/08 08:06
S14	1	substrate wafer semiconductor) and (docking adj station) and (proximity adj head)	US-PG&UB USPAT; USOCR	OR	ON	2007/08/08 08:07
S15	267	substrate wafer semiconductor) and (proximity adj head)	US-PG&UB USPAT; USOCR	OR	ON	2007/08/08 08:32
S16	602507	substrate wafer semiconductor) and (level\$) and docking station	US-PG&UB USPAT; USOCR	OR	ON	2007/08/08 08:33
S17	1118	substrate wafer semiconductor) and (level\$) and (docking adj station)	US-PG&UB USPAT; USOCR	OR	ON	2007/08/08 08:34
S18	169	substrate wafer semiconductor) and (level\$) same (docking adj station)	US-PG&UB USPAT; USOCR	OR	ON	2007/08/08 08:43

S19	87	substrate wafer semiconductor) and (level\$3) same (docking adj station) and (clean\$3 etch\$3 coat\$3)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/08 08:44
S20	36	substrate wafer semiconductor) and (level\$3) same (docking adj station) and (clean\$3 etch\$3 coat\$3) and quartz	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/08 18:03
S21	3	"54725/2" "6491764" "6398975" ).pn.	USPAT	OR	ON	2007/08/08 09:53
S22	1	substrate wafer semiconductor) and (level\$3) same (docking adj station) same quartz and (clean\$3 etch\$3 coat\$3)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/08 18:05
S23	1	substrate wafer semiconductor) same (docking adj station) same quartz and (clean\$3)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/08 18:05
S24	20634	substrate wafer semiconductor) same quartz and (clean\$3)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/08 18:06
S25	1230	substrate wafer semiconductor) same (quartz and hydrophilic) and (clean\$3)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/08 18:08
S26	125	substrate wafer semiconductor) same (quartz and hydrophilic) same (clean\$3)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/08 18:08
S27	121	substrate wafer semiconductor) same (quartz and hydrophilic) same (clean\$3)	US-PGRUB; USPAT	OR	ON	2007/08/08 18:32
S28	80	substrate wafer semiconductor) same quartz same hydrophilic same (clean\$3)	US-PGRUB; USPAT	OR	ON	2007/08/08 18:16
S29	0	substrate wafer semiconductor) same quartz same hydrophilic same (clean\$3) same chuck	US-PGRUB; USPAT	OR	ON	2007/08/08 18:16
S30	2	substrate wafer semiconductor) same quartz same hydrophilic same (clean\$3) and chuck	US-PGRUB; USPAT	OR	ON	2007/08/08 18:18
S31	356	substrate wafer semiconductor) same quartz same (clean\$3) and chuck	US-PGRUB; USPAT	OR	ON	2007/08/08 18:24
S32	1	substrate wafer semiconductor) same quartz same (clean\$3) and chuck and hydrophilic	US-PGRUB; USPAT	OR	ON	2007/08/08 18:22
S33	1	"5819434".pn.	US-PGRUB; USPAT	OR	ON	2007/08/08 18:21
S34	1	substrate wafer semiconductor) same quartz same (clean\$3) and (chuck holder pedestal) and hydrophilic	US-PGRUB; USPAT	OR	ON	2007/08/08 18:22
S35	1	substrate wafer semiconductor) same quartz same (clean\$3) and (chuck holder pedestal) and hydrophilic	US-PGRUB; USPAT	OR	ON	2007/08/08 18:22
S36	2	substrate wafer semiconductor) same quartz same (clean\$3) and (chuck holder pedestal docking magazine) and hydrophilic	US-PGRUB; USPAT	OR	ON	2007/08/08 18:27
S37	2	substrate wafer semiconductor) same quartz same (chuck holder pedestal docking magazine station) same hydrophilic	US-PGRUB; USPAT	OR	ON	2007/08/08 18:27
S38	2	substrate wafer semiconductor) and quartz same (chuck holder pedestal docking magazine station) same hydrophilic	US-PGRUB; USPAT	OR	ON	2007/08/08 18:28
S39	2	substrate wafer semiconductor) and quartz same (chuck holder pedestal docking magazine station table) same hydrophilic	US-PGRUB; USPAT	OR	ON	2007/08/08 18:29
S40	2	substrate wafer semiconductor) and quartz same (chuck holder pedestal stage platform docking magazine station table) same hydrophilic	US-PGRUB; USPAT	OR	ON	2007/08/08 18:29
S41	14	substrate wafer semiconductor) and (apparatus chuck docking station platform holder) same (quartz and hydrophilic) same (clean\$3)	US-PGRUB; USPAT	OR	ON	2007/08/09 07:45
S42	228	substrate wafer semiconductor) and (apparatus chuck docking station platform holder) same (quartz and hydrophilic)	US-PGRUB; USPAT	OR	ON	2007/08/08 18:35
S43	23	"4967777"	US-PGRUB; USPAT	OR	ON	2007/08/09 07:45

S44	1	"4967777".pn.	US-PGRUB; USPAT	OR	ON	2007/08/09 10:48
S45	1	"2020115024"	US-PGRUB; USPAT	OR	ON	2007/08/09 10:15
S46	1	"6247479".pn.	US-PGRUB; USPAT	OR	ON	2007/08/09 10:24
S47	1	"6162302".pn.	US-PGRUB; USPAT	OR	ON	2007/08/09 10:24
S48	36	"6399979" "6491764" "4838289" "5271774" "5705223" "5945351" "5997653" "6341998" "6391166" "5660642" "5807922" "5630334" "5882433" "5975098" "5989478" "6132986" "6531206" "6789584" "6854473" "6854993" "6888326" "6888327" "7000622" "7069937" "4086870" "5294257" "6514570" "5709757" "5830334" "5882433" "5893004" "5975098" "5989478" "6066454" "6092937" "6103636" "6108932" "6132586" "6214513" "6230722" "6417117" "6433541" "6474788" "6488040" "6495005" "6530823" "6531206" "6550588" "6655017" "6616772" "6669323" "6764720" "3853285" "4367123" "4444492" "5102494" "5180431" "5343234" "5361449" "5472502" "5558111" "5601655".pn.	USPAT	OR	ON	2007/08/09 11:03
S49	0	(ball adj dent near3 vertic\$4 same (substrate wafer semiconductor))	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/20 15:02
S50	0	(ball adj dent) near3 vertic\$4 same (substrate wafer semiconductor)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/20 15:00
S51	0	(ball adj dent) near3 vertic\$4 and (substrate wafer semiconductor)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/20 15:00
S52	0	(ball adj dent) same vertic\$4 and (substrate wafer semiconductor)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/20 15:01
S53	0	(ball adj dent) same vertic\$3 and (substrate wafer semiconductor)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/20 15:01
S54	0	(ball adj dent) same vertic\$4 and (substrate\$ wafer\$ semiconductor\$)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/20 15:01
S55	0	(ball adj dent) same vertic\$5 and (substrate\$ wafer\$ semiconductor\$)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/20 15:02
S56	1	(ball adj dent) near3 vertic\$4 same (substrate wafer semiconductor)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/20 15:02
S57	19	(ball adj dent) same vertic\$5 and (substrate\$ wafer\$ semiconductor\$)	US-PGRUB; USPAT; USOCR	OR	ON	2007/08/20 15:02
S58	0	(woods near carl).in. and california	US-PGRUB; USPAT	OR	ON	2008/03/03 10:54
S59	40	(woods near carl).in. and (wafer semiconductor substrate)	US-PGRUB; USPAT	OR	ON	2008/03/03 10:54
S60	13	(woods near carl).in. and (wafer semiconductor substrate)	EPO; JPO; DERWENT; IBM_TOB	OR	ON	2008/03/03 10:59
S61	40	(garcia adj james).in. and (wafer semiconductor substrate)	US-PGRUB; USPAT; EPO; JPO; DERWENT; IBM_TOB	OR	ON	2008/03/03 11:03
S62	1250	134/30 cds.	US-PGRUB; USPAT	OR	ON	2008/03/03 11:06
S63	553	134/30 cds. and (semiconductor wafer substrate)	US-PGRUB; USPAT	OR	ON	2008/03/03 11:07
S64	665	134/31 cds.	US-PGRUB; USPAT	OR	ON	2008/03/03 11:20

S65	0	2003/0015216.pn.	US-PGRUB; USPAT	OR	ON	2008/03/03 11:26
S66	1	20030015216".pn.	US-PGRUB; USPAT	OR	ON	2008/03/03 11:26
S67	30	"20020115024"   "20020121290"   "20020125212"   "20040211447"   "40868701"   "46382889"   "5271774"   "5294257"   "53505002"   "5660642"   "5705223"   "5807522"   "5830034"   "5882433"   "5945351"   "5975098"   "5989478"   "5997653"   "6132586"   "6162302"   "6247479"   "6341998"   "6391186"   "6398975"   "6446358"   "6488040"   "6491764"   "6514570"   "6531206"   "6629540".PN.	US-PGRUB; USPAT	OR	ON	2008/03/03 13:47
S68	0	134/202.cds	US-PGRUB; USPAT; USOCR	OR	ON	2008/03/03 13:53
S69	723	134/201.cds	US-PGRUB; USPAT; USOCR	OR	ON	2008/03/03 13:53
S70	2035	134/902.cds	US-PGRUB; USPAT; USOCR	OR	ON	2008/03/03 14:10
S71	1920	134/902.cds and (semiconductor substrate wafer)	US-PGRUB; USPAT; USOCR	OR	ON	2008/03/03 14:10
S72	1	"6247479".pn.	US-PGRUB; USPAT; USOCR	OR	ON	2008/03/04 15:09

3/4/2008 5:08:52 PM

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